



Advanced Processes for 193-nm Immersion Lithography (SPIE Press Monograph Vol. PM189)

Yayi Wei, Robert L. Brainard

[Download now](#)

[Click here](#) if your download doesn't start automatically

Advanced Processes for 193-nm Immersion Lithography (SPIE Press Monograph Vol. PM189)

Yayi Wei, Robert L. Brainard

Advanced Processes for 193-nm Immersion Lithography (SPIE Press Monograph Vol. PM189) Yayi Wei, Robert L. Brainard

This book is a comprehensive guide to advanced processes and materials used in 193-nm immersion lithography (193i). It is an important text for those new to the field as well as for current practitioners who want to broaden their understanding of this latest technology. The book can be used as course material for graduate students of electrical engineering, material sciences, physics, chemistry, and microelectronics engineering and can also be used to train engineers involved in the manufacture of integrated circuits. It provides techniques for selecting critical materials (topcoats, photoresists, and antireflective coatings), and optimizing immersion processes to ensure higher performance and lower defectivity at lower cost. This book also includes sections on shrinking, trimming, and smoothing of the resist pattern to reduce feature sizes and line-edge roughness. Finally, it describes the recent development of 193i in combination with double exposure and double patterning.

Contents

- Immersion Lithography and its Challenges
- Process Steps in the Track
- Resist Leaching and Water Uptake
- Contact Angle of Water on Resist Stacks
- Topcoat and Resist for Immersion Lithography
- Immersion Defects and Defect Reduction Strategies
- Antireflection Coatings and Underlayer Technology
- Resist Shrink and Trim Processes
- Double Exposures and Double Patterning
- Line-edge Roughness of Resist Patterns
- Extendibility of 193-nm Immersion Lithography (193i+)

 [Download Advanced Processes for 193-nm Immersion Lithograph ...pdf](#)

 [Read Online Advanced Processes for 193-nm Immersion Lithogra ...pdf](#)

Download and Read Free Online Advanced Processes for 193-nm Immersion Lithography (SPIE Press Monograph Vol. PM189) Yayi Wei, Robert L. Brainard

From reader reviews:

Earl Goodman:

Have you spare time for a day? What do you do when you have much more or little spare time? That's why, you can choose the suitable activity intended for spend your time. Any person spent their own spare time to take a wander, shopping, or went to the actual Mall. How about open or maybe read a book eligible Advanced Processes for 193-nm Immersion Lithography (SPIE Press Monograph Vol. PM189)? Maybe it is to be best activity for you. You realize beside you can spend your time along with your favorite's book, you can more intelligent than before. Do you agree with it is opinion or you have some other opinion?

Kathy Norvell:

What do you consider book? It is just for students since they are still students or the item for all people in the world, what best subject for that? Merely you can be answered for that query above. Every person has diverse personality and hobby per other. Don't to be obligated someone or something that they don't would like do that. You must know how great along with important the book Advanced Processes for 193-nm Immersion Lithography (SPIE Press Monograph Vol. PM189). All type of book can you see on many methods. You can look for the internet solutions or other social media.

Latashia Bartlett:

Now a day those who Living in the era wherever everything reachable by match the internet and the resources inside can be true or not demand people to be aware of each info they get. How individuals to be smart in receiving any information nowadays? Of course the reply is reading a book. Reading through a book can help folks out of this uncertainty Information mainly this Advanced Processes for 193-nm Immersion Lithography (SPIE Press Monograph Vol. PM189) book because book offers you rich information and knowledge. Of course the info in this book hundred per cent guarantees there is no doubt in it as you know.

Joan Toon:

The publication with title Advanced Processes for 193-nm Immersion Lithography (SPIE Press Monograph Vol. PM189) includes a lot of information that you can study it. You can get a lot of advantage after read this book. This specific book exist new understanding the information that exist in this reserve represented the condition of the world today. That is important to yo7u to be aware of how the improvement of the world. This specific book will bring you within new era of the glowbal growth. You can read the e-book with your smart phone, so you can read the item anywhere you want.

**Download and Read Online Advanced Processes for 193-nm
Immersion Lithography (SPIE Press Monograph Vol. PM189) Yayi
Wei, Robert L. Brainard #7LPIVYU6RSD**

Read Advanced Processes for 193-nm Immersion Lithography (SPIE Press Monograph Vol. PM189) by Yayi Wei, Robert L. Brainard for online ebook

Advanced Processes for 193-nm Immersion Lithography (SPIE Press Monograph Vol. PM189) by Yayi Wei, Robert L. Brainard Free PDF d0wnl0ad, audio books, books to read, good books to read, cheap books, good books, online books, books online, book reviews epub, read books online, books to read online, online library, greatbooks to read, PDF best books to read, top books to read Advanced Processes for 193-nm Immersion Lithography (SPIE Press Monograph Vol. PM189) by Yayi Wei, Robert L. Brainard books to read online.

Online Advanced Processes for 193-nm Immersion Lithography (SPIE Press Monograph Vol. PM189) by Yayi Wei, Robert L. Brainard ebook PDF download

Advanced Processes for 193-nm Immersion Lithography (SPIE Press Monograph Vol. PM189) by Yayi Wei, Robert L. Brainard Doc

Advanced Processes for 193-nm Immersion Lithography (SPIE Press Monograph Vol. PM189) by Yayi Wei, Robert L. Brainard Mobipocket

Advanced Processes for 193-nm Immersion Lithography (SPIE Press Monograph Vol. PM189) by Yayi Wei, Robert L. Brainard EPub